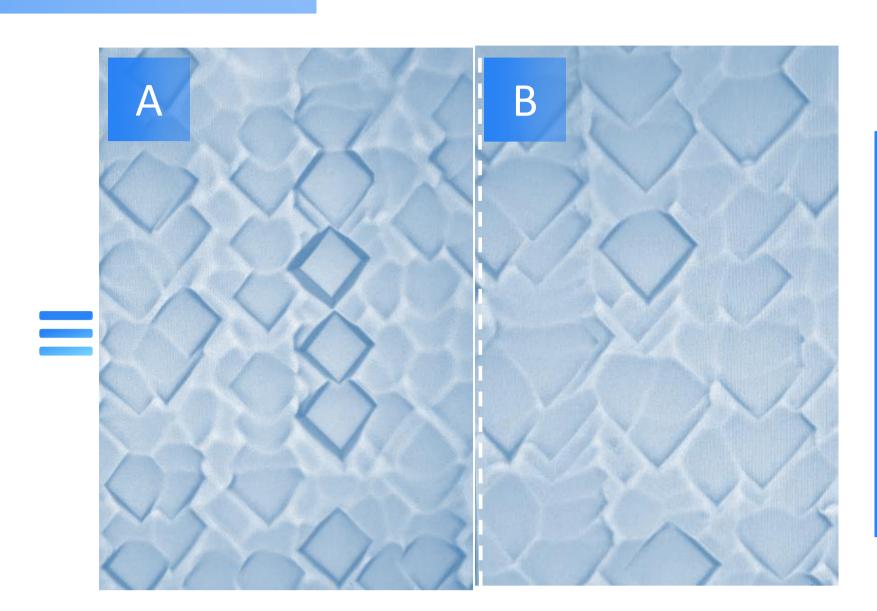
Alkaline Polishing Additive BPL-719

Similar efficiency across different etch weights

Weight Control:

Large Window for Etch

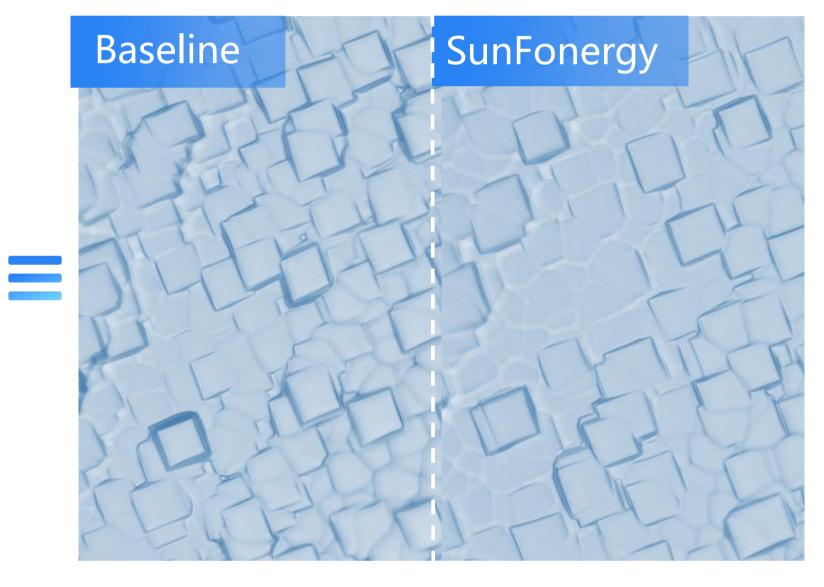


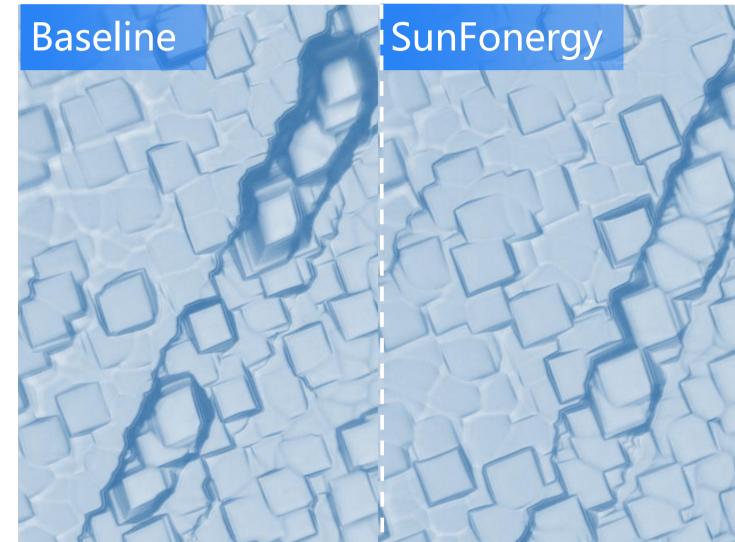
A: 182mm wafer
0.21g etch weight

B: 182mm wafer
0.25g etch weight

Better Morphology:

More uniform surface, smoother overlays among pyramid bases.





Higher Efficiency

Higher efficiency than competitors and stable performance throughout lifetime

| Item | Eta | Uoc | Isc | FF | IRev2 | Rs | Rsh |
|------------|-------|--------|--------|-------|-------|--------|--------|
| Baseline | 22.88 | 0.6862 | 13.496 | 81.57 | 0.073 | 0.0018 | 663.12 |
| SunFonergy | 22.89 | 0.6869 | 13.484 | 81.60 | 0.078 | 0.0018 | 667.21 |

High Adaptability:

SunFonergy's additive can be used with both hot O_3 (inline and batch type) and wet O_3 processes.









Strong Cleaning Power:

SunFonergy's additive can more effectively remove wafer residues, resulting in a cleaner alkaline polishing process.



More Uniform Surface:

Smoother overlays among polished pyramid bases.



Cost Effective:

Reduces the post-cleaning bath's alkaline chemical concentration and/or removes the post-cleaning step.



Strong Front-Side Protection:

SunFonergy's additive offers strong front-side protection under stress-tested conditions (high temperature, long duration, etc).